

PATENT ASSIGNMENT

Electronic Version v1.1

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SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT
CONVEYING PARTY DATA	
Name	Execution Date
DAINIPPON SCREEN MFG. CO., LTD.	09/30/2006
RECEIVING PARTY DATA	
Name:	Sokudo Co., Ltd.
Street Address:	K-I Shijo Building, 88 Kankoboko-cho
Internal Address:	Shijodori-Muromachi-Higashiiru, Shimogyo-ku
City:	Kyoto
State/Country:	JAPAN
Postal Code:	600-8009
PROPERTY NUMBERS Total: 1	
Property Type	Number
Patent Number:	5762709
CORRESPONDENCE DATA	
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ATTORNEY DOCKET NUMBER:	026531-008500US
NAME OF SUBMITTER:	Craig C. Largent
Total Attachments: 2	
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PATENT
REEL: 018524 FRAME: 0843

ADDITIONAL ASSIGNMENT OF PATENTS

This ADDITIONAL ASSIGNMENT OF PATENTS (this "Assignment") granted by **Dainippon Screen Mfg. Co., Ltd.**, a Japanese *kabushiki kaisha*, ("Transferor") to Sokudo Co., Ltd., a Japanese *kabushiki kaisha*, ("Company") is made effective as of September 30, 2006.

RECITALS

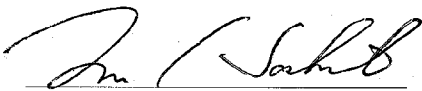
WHEREAS, Transferor desires to transfer and assign to Company, and Company desires to accept the transfer and assignment of all of Transferor's worldwide right, title, and interest in, to, and under such patents and the patent application as set forth in Appendix A; and

NOW THEREFORE, accordance with Section 4.11(a) and Section 7.3 (c) of the Maser Agreement signed by Transferor and Applied Materials, Inc. on May 15, 2006 and for and in consideration of covenants and agreements set forth below and other good and valuable consideration, the receipt and sufficiency of which are hereby acknowledged:

1. Transferor hereby additionally assign, delivers, transfers, and conveys unto Company, all right, benefits, title, and interest in and to the patents and the patent application set forth in Appendix A (collectively, the "Patents"), and all future patents which may be granted there from throughout the world and all divisions, reissues, reexaminations, substitutions, continuations, foreign counterparts and extension of the Patents (collectively "Future Patents"); and Transferor hereby authorizes and requests the United States Patent and Trademark Office and other patent offices throughout the world to issue all Future Patents, insofar as Transferor's interest is concerned, to Company.
2. Transferor will execute any and all powers of attorney, applications, assignments, declarations, affidavits, and any other papers in connection therewith reasonably necessary to perfect such right, benefit, title, and interest in Company.

IN WITNESS WHEREOF, Transferor has caused this Assignment to be executed by its duly authorized corporate officer effective as of the date first written above.

Dainippon Screen Mfg. Co., Ltd.



Name: Masahiro Hashimoto

Its: President & COO

Date: October 20, 2006



Patents and Patent Applications to transfer from DNS to Sokudo								
DNS Ref. No.	Title	Country	Application No.	Filing Date	Publication No.	Publication Date	Patent No.	Issue Date
P04993-KR	Apparatus for Exposing Periphery of an Object	KR	90-06042	1990/4/28	91-19141	1991/11/30	69876	1994/1/13
P04993-US	Apparatus for Exposing Periphery of an Object	US	004788	1993/1/14	n/a	n/a	5289263	1994/2/22
P07069-KR	Spin Coating Apparatus and Method	KR	95-52502	1995/12/20	96-21171	1996/7/18	158527	1998/8/5
P07069-US	Spin Coating Apparatus	US	577827	1995/12/22	n/a	n/a	5865893	1999/2/2
P05981B	Apparatus For Processing Substrate	JP	H08-051137	1996/3/8	H08-243466	1996/9/24	02756777	1998/3/13
P07204-US	Method of and Apparatus for Forming Film on Substrate by Sensing Atmospheric Pressure	US	633484	1996/4/17	n/a	n/a	5766671	1998/6/16
P07275-US	Coating Method of Coating Solution	US	662216	1996/6/11	n/a	n/a	5843527	1998/12/1
P07275-KR	Coating Method of Coating Solution	KR	95-21494	1996/6/14	97-359	1997/1/21	199463	1999/3/5
P07330-KR	Substrate Spin Coating Apparatus	KR	96-28567	1996/7/15	97-8330	1997/2/24	244171	1999/11/22
P07330-US	Substrate Spin Coating Apparatus	US	680983	1996/7/16	n/a	n/a	5762709	1998/6/9
P08559	Apparatus and Method for Development	JP	H09-110816	1997/4/28	H10-303103	1998/11/13	03566026	2004/6/18
P08293-US	Developing Apparatus and Developing Method	US	997083	1997/12/23	n/a	n/a	5984540	1999/11/16
P11176-KR	Coating Method of Coating Solution	KR	1999-49370	1999/11/9			3655042	2002/12/4
P12934-US	Developing Apparatus and Developing Method	US	305911	2002/11/26	2003-185560	2003/10/2	6752544	2004/6/22
P13352-US	Thermal processing apparatus, thermal processing method, and substrate processing apparatus	US	10/926718	2004/8/26	2005/0058440	2005/3/17		

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